



IFK

PATENT
Customer No. 22,852
Attorney Docket No. 04329.3147

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Kyoko Izuha, et al.) Group Art Unit: 1756
)
Serial No.: 10/668,245) Examiner: ROSASCO, Stephen D.
)
Filed: September 24, 2003) Confirmation No.: 2059
)
For: MASK, MANUFACTURING METHOD)
FOR MASK, AND MANUFACTURING)
METHOD FOR SEMICONDUCTOR)
DEVICE)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In a restriction requirement mailed August 2, 2005, the period for response to which extends through September 2, 2005, the Examiner required restriction under 35 U.S.C. § 121 between Group I, claims 1-37, characterized by the Examiner as drawn to a mask and method for making; and Group II, claims 38-47, drawn to a method of manufacturing a semiconductor device. Applicants elect to prosecute Group I, claims 1-37, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNE, L.L.P.

Dated: September 2, 2005

By:

Richard V. Burgujian
Richard V. Burgujian
Reg. No. 31,744

#27,432